



503:38156X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: YOSHIOKA, et al.

Serial No.: 09/493,104

Filed: January 28, 2000

For: METHOD OF PROCESSING SPECIMENS, AND APPARATUS THEREFOR AND A METHOD OF MANUFACTURE OF A MAGNETIC HEAD

Art Group: 1746

Examiner: A. Olsen

SP
AS
9/16/02

AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

September 9, 2002

Sir:

In response to the Office Action mailed May 9, 2002, the time period for responding having been extended one month until September 9, 2002, please amend the above-identified application as follows:

IN THE CLAIMS:

Please amend Claims 1 - 4 and 13 - 22 as follows:

1. (Twice amended) A method of processing a specimen comprising:
- a first step of etching a specimen, which is a lamination layer formed on a substrate and includes at least one layer made of NiFe alloy or NiFeCo alloy, by gas plasma with a gas which contains chlorine at a temperature of the specimen below 200°C in an etching chamber;

C1

Sub D-1

RECEIVED
SEP 12 2002
TC 1700